

Single Wafer (Dip type) Cleaning Hood



Basic Specifications

Wafer	φ300 mm, φ 200mm , φ150mm
Carrying Cassette	Open Cassette / FOUP / Standard Cassette
Processing Cassette	None (Carrier-less)
Number of Wafers	1 wafer/batch
Chemical tanks	APM, SPM, HPM, HF, BHF, H ₃ PO ₄
Dryer	IR Lamp heating
Operation	Full automatic / Semi automatic